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Investigation of effective-medium models of microscopic surface roughness by spectroscopic ellipsometry

DOI: 10.1103/physrevb.20.3292  
Physical Review B, 1979, 20, 3292-3302.

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#	Paper	IF	Citations
895	Real-time and spectroscopic ellipsometry of film growth: Application to multilayer systems in plasma and CVD processing of semiconductors. <b>1980</b> , 96, 275-293		35
894	An investigation of ion-bombarded and annealed <111> surfaces of Ge by spectroscopic ellipsometry. <b>1980</b> , 96, 294-306		57
893	Interface ellipsometry: An overview. <b>1980</b> , 101, 84-98		22
892	Approximate solution of ellipsometric equations for optically biaxial crystals. <b>1980</b> , 70, 1275-7		217
891	Optical properties of Au: Sample effects. <i>Physical Review B</i> , <b>1980</b> , 21, 3290-3299	3.3	267
890	Optical effects of energetic copper-ion irradiation on copper mirrors. <b>1981</b> , 20, 4062-72		1
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886	Optical properties of low-pressure chemically vapor deposited silicon over the energy range 3.08.0 eV. <i>Applied Physics Letters</i> , <b>1981</b> , 38, 56-58	3.4	75
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19	Structure-dependent optical nonlinearity of indium tin oxide. <i>Applied Physics Letters</i> , <b>2022</b> , 120, 101901	3.4	2
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